

Special Invited Session 19

Micro/Nanofabrication Techniques and Devices

Micro- and nanofabrication technologies are enabling unprecedented advances in sensors, actuators, flexible electronics, and emerging quantum and neuromorphic devices. This session focuses on recent progress in high-resolution lithography, atomic-scale patterning, additive and subtractive manufacturing, heterogeneous integration, and novel materials platforms such as 2D materials, MEMS/NEMS structures, and monolithic 3D architectures.

Special Invited Session Chairs



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Paper Submission

For the initial submission, the authors can select one of the following two types:

- Type 1: full paper (4-6 pages)
- Type 2: extended abstract (2 pages)

*Note:

- View more on website:

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- Step 1: Please select the track “**Special Invited Sessions**” and click “**Continue**.”
- Step 2: After filling in the basic paper information, please select the topic “**SIS19 – Micro/Nanofabrication Techniques and Devices**.”



Important Dates

Initial Submission (Full Paper or Extended Abstract)	Jan. 10, 2026
Notification of Acceptance	Feb. 10, 2026
Late-News Submission Deadline	Feb. 28, 2026
Early Registration Deadline	Mar. 10, 2026
Presentation-Only Submission Deadline	Mar. 10, 2026
Final Submission Deadline	Mar. 10, 2026

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